Docket No.: 49657-961

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

Kenji ITOGA, et al.

Serial No.: 09/769,490

Filed: January 26, 2001

MAR 1 8 2004 WAR 1

Customer Number: 20277

Confirmation Number: 5521

Group Art Unit: 2882

Examiner: C. Kao

For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK, X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON RADIATION METHOD AND SEMICONDUCTOR DEVICE

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

<u>Transmitted</u> herewith is a Supplemental Amendment in the above-identified application.

No additional fee is required.

Applicant is entitled to small entity status under 37 CFR 1.27

Also attached:

The fee has been calculated as shown below:

	NO. OF CLAIMS	HIGHEST PREVIOUSLY PAID FOR	EXTRA CLAIMS	RATE	FEE
Total Claims	21	21	0	\$18.00 =	\$0.00
Independent Claims	8	8	0	\$86.00 =	\$0.00
	6.0	Multiple claims newly presented			\$0.00
		Fee for extension of time			\$0.00
					\$0.00
			Total of Ab	ove Calculations	\$0.00

Please charge my Deposit Account No. <u>500417</u> in the amount of \$0.00. An additional copy of this transmittal sheet is submitted herewith.

The Commissioner is hereby authorized to charge payment of any fees associated with this communication or credit any overpayment, to Deposit Account No. 500417, including any filing fees under 37 CFR 1.16 for presentation of extra claims and any patent application processing fees under 37 CFR 1.17.

Respectfully submitted,

MCDERMOTT, WILL & EMERY

Scott D. Paul

Registration No. 42,984

600 13th Street, N.W. Washington, DC 20005-3096 (202) 756-8000 SDP:kap Facsimile: (202) 756-8087 **Date: March 18, 2004** Docket No.: 49657-961 PATENT

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For: X-RAY EXPOSURE APPARATUS, X-RAY EXPOSURE METHOD, X-RAY MASK,

X-RAY MIRROR, SYNCHROTRON RADIATION APPARATUS, SYNCHROTRON

RADIATION METHOD AND SEMICONDUCTOR DEVICE

SUPPLEMENTAL AMENDMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

The following Amendment and Remarks are submitted in response to the Office Action dated September 16, 2003, and supplemental to the Amendment filed February 17, 2004.